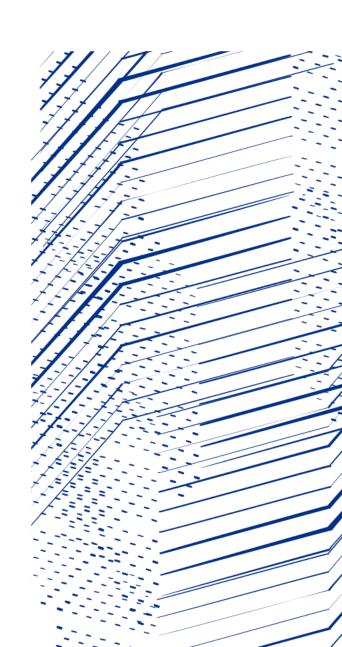


6th IFAST WP9 Meeting





6 GHz Cavity deposition



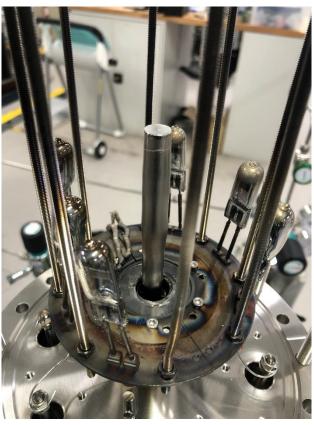
Close Cavity

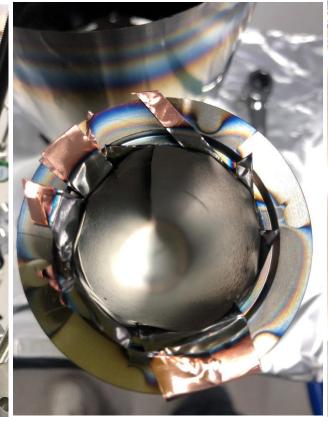


Open cavity

Nb deposition using coil magnet









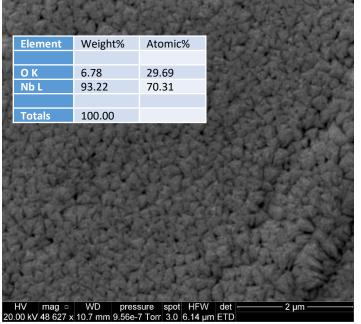
Deposition parameters: Power 100W Current 0.22A

Voltage 453V Dep Temp room Temp DC

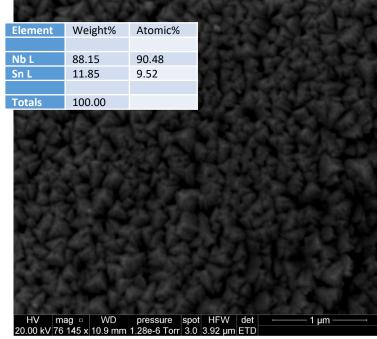
Deposition time 1 hour Dep pressure 2 x10⁻² mbar

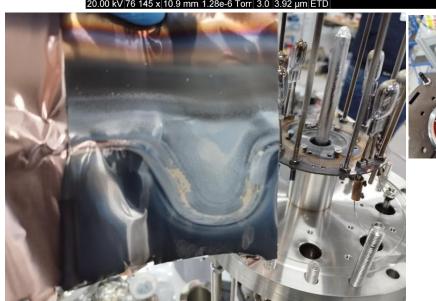
mag current 4.0A

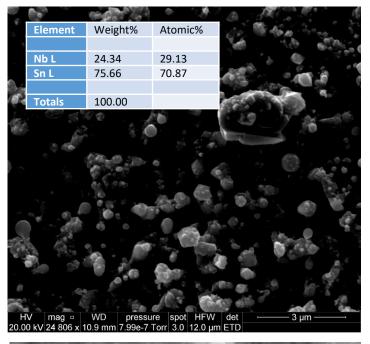
Nb3Sn deposition with Nb tube and Sn wire inside



ON THE REAL PROPERTY.		EL BELLEVI	щ
Element	Weight%	Atomic%	
A11 A	00	07.04	- 6
Nb L	84.73	87.64	- 5
Sn L	15.27	12.36	
			556
Totals	100.00		200
1000	1944	+ - 34	200
		ASSESSED BY	
4.35		300	
1000	的原理問題		
34215	100	MAN SAN	
		EAAC	
可用位于 多	2000	300	
	باحديد ب		
September 1	125	120	Section 1
企为相談的	***		
	Section 2	2000年展	1000
		国际现代证	
	STRAGE		2000
HV mag □	WD pres	sure spot H	FW det
0.00 kV 49 724	10.7 mm 9.66e-	7 Torr 3.0 6.0	0 µm ETD

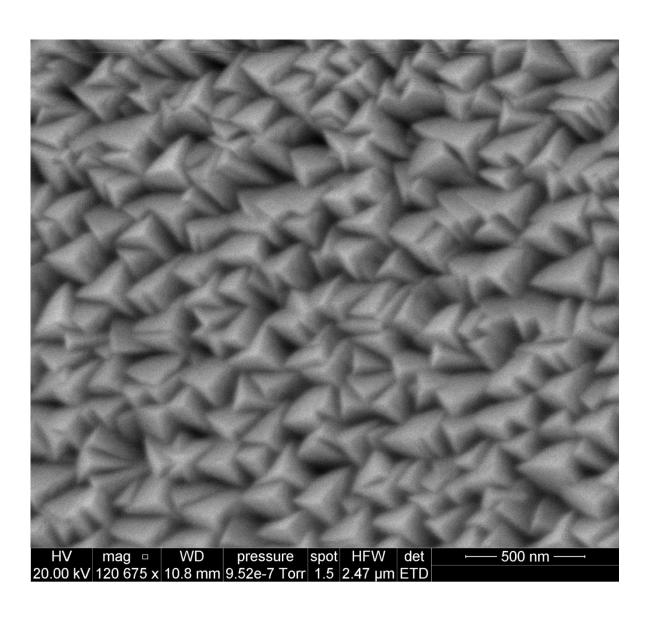


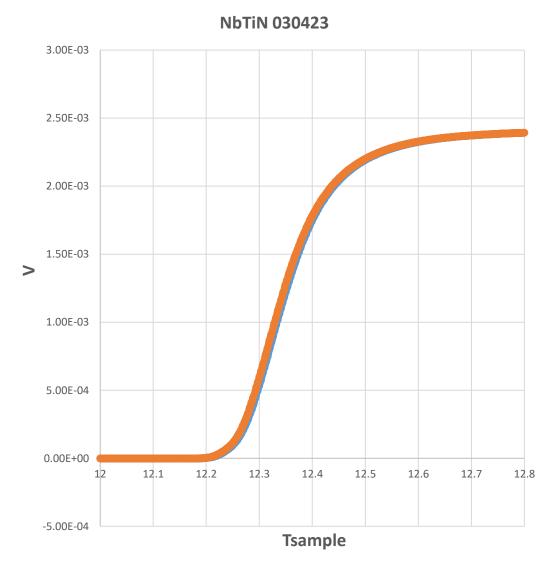




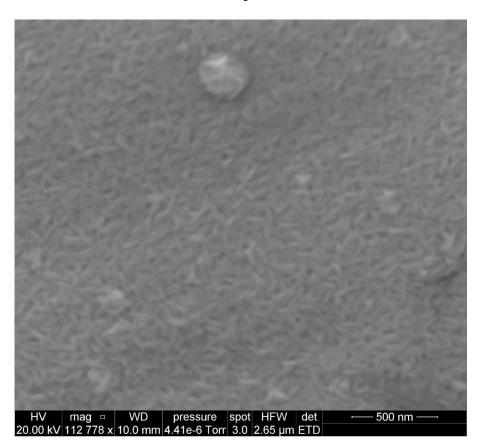
Element	Weight%	Atomic%
Nb L	30.62	36.05
Sn L	69.38	63.95
Totals	100.00	
Totals	100.00	
		100
F 6502		AND 1
HV mag □	WD pre	ssure spot
20 00 kV 31 456	x 10 9 mm 1 47e	-6 Torr 3.0 9

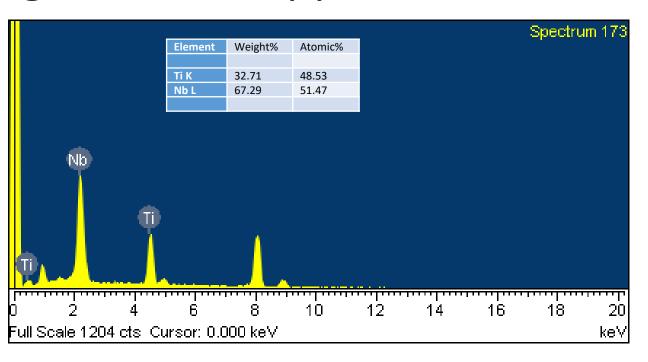
NbTiN deposition using Nb₃₇Ti₆₃ rod





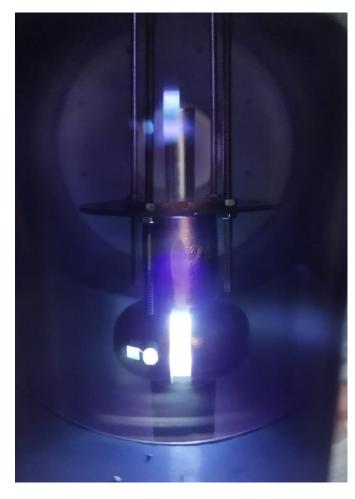
NbTiN deposition using Nb rod wrapped with Ti wire

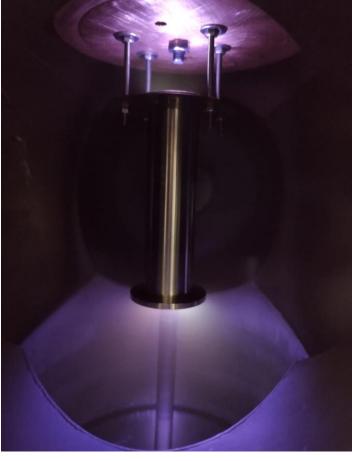


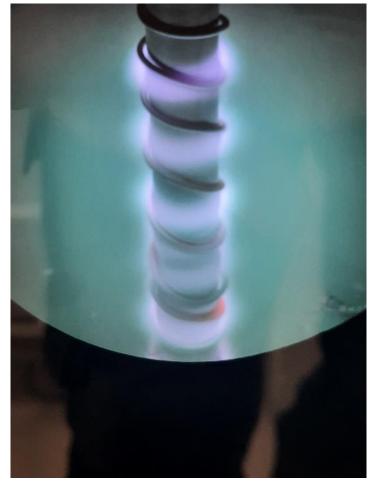


The ratio of Nb to Ti can be adjusted for optimum performance stoichiometry

Nb/NbTiN using permanent magnet magnetron





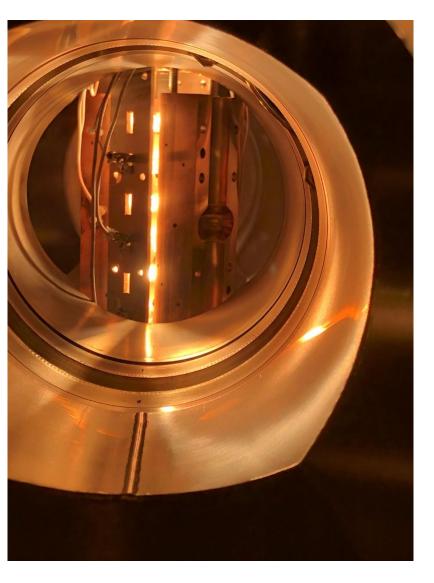


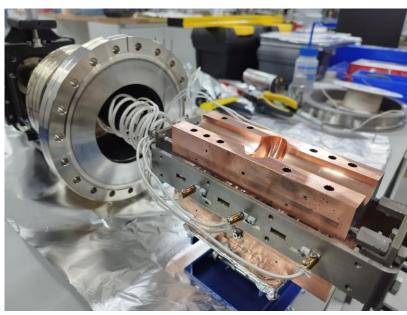
Close cavity

Tube

For A15 and B1 superconducting deposition

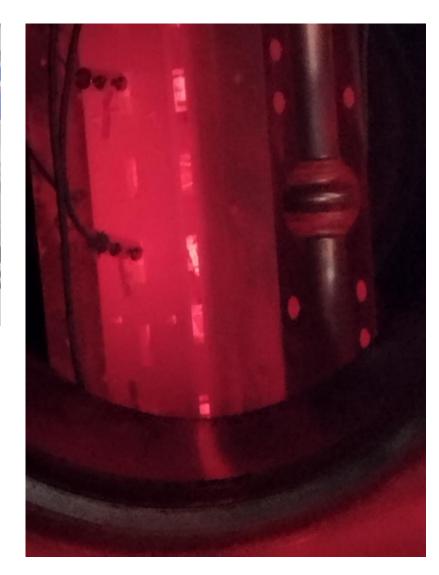
6 GHz open cavity heating stage





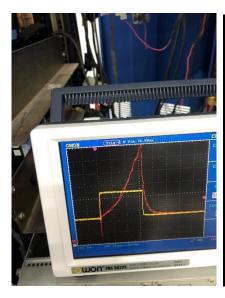
Without any heat shield the cavity temperature reaches to 600 C





1.3 GHz cavity

HIPIMS dep of Nb on half cell 1.3 GHz cavity RT



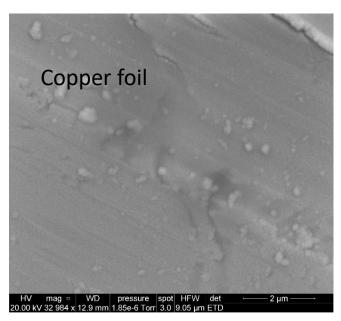


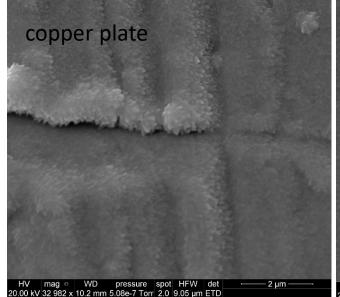


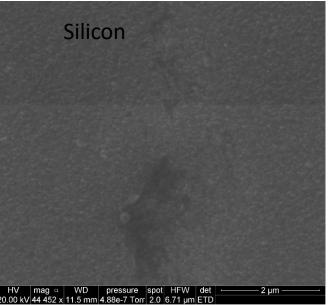






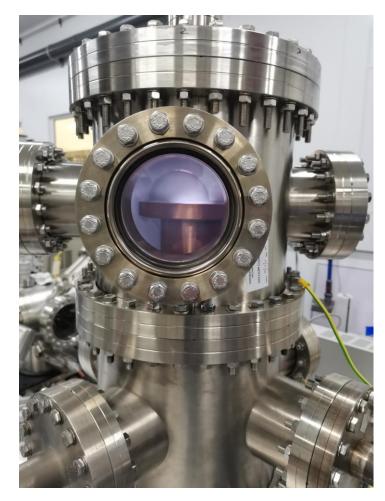








Plasma diagnostic study with Liverpool University

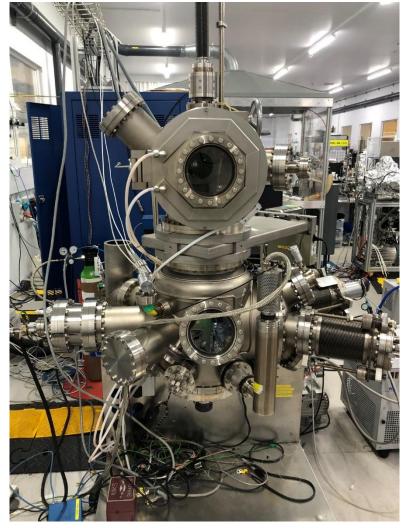






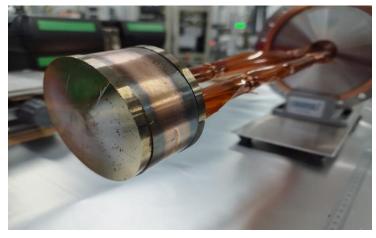


1.3 GHz Cavity deposition system



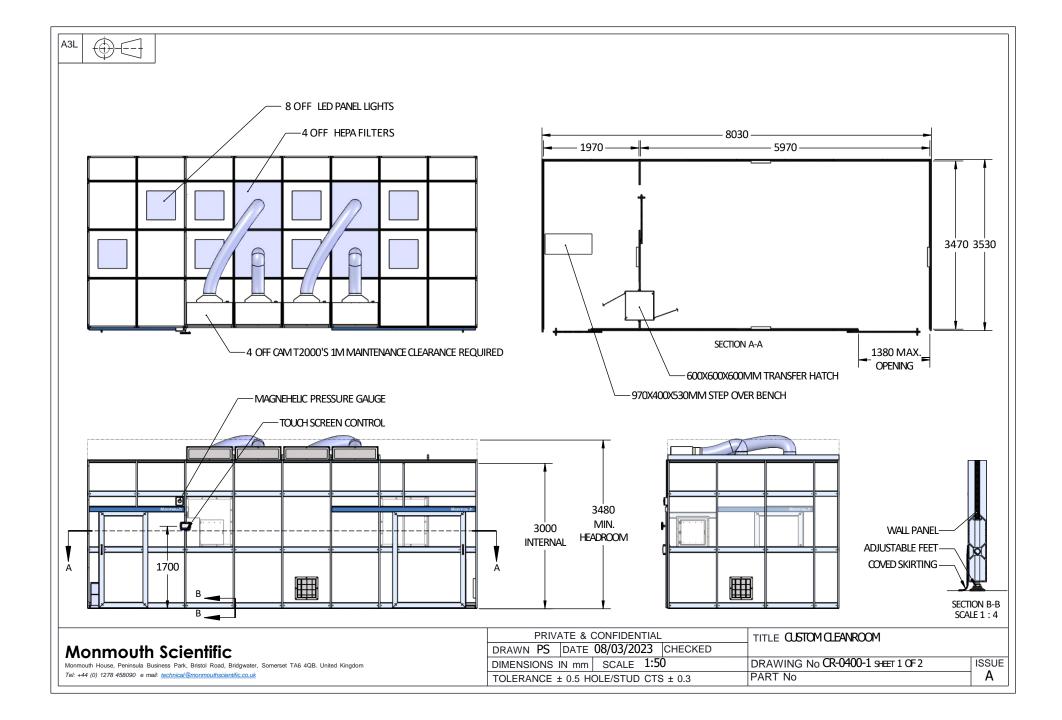






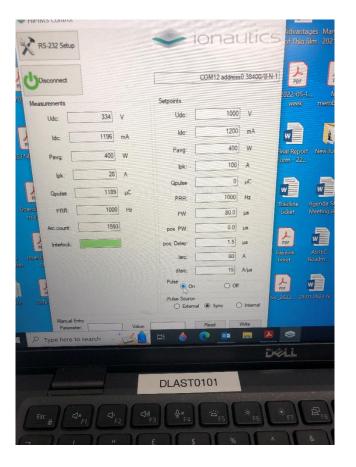
The system is equipped with load lock chamber, rotating arm that can turn and move up and down, the chamber wall is water cooled, fixed magnetron in the centre.

It will be positioned in an ISO 6 clean room with ISO 4 cabinet for final cavity preparation.

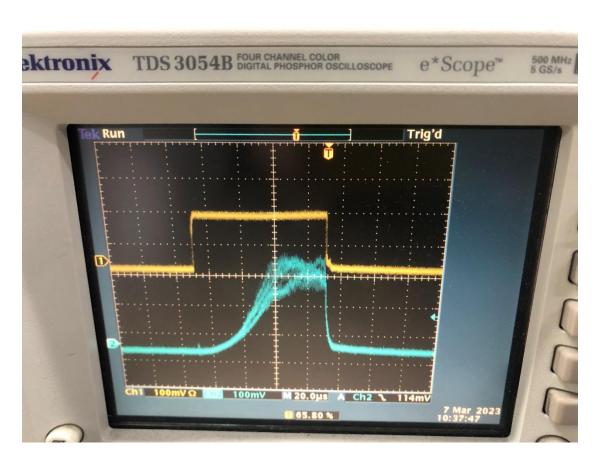


Planar sample deposition

HIPIMS deposition of Nb on Dia Copper from RT to 650 C







Additional analytical systems



Secondary Ion Mass spectrometry SIMS/SMNS: Both static and dynamic SIMS Cs for negative ions and Oxygen for positive ions Detection limit ppm.



FE SEM
Large sample
Compatible with ion beam milling
EDX mapping and 3D topography
EBSD

1 metre NEG coating facility commissioned for 20 mm and 38 mm ID for both Cu and SS

